



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

VON AMMON ET AL.

Group Art Unit: 2823

Serial No.: 10/809,070

Examiner: Jarrett J. Stark

Filed: March 25, 2004

For: METHOD AND DEVICE FOR THE PRODUCTION OF A  
SILICON SINGLE CRYSTAL SILICON SINGLE CRYSTAL,  
AND SILICON SEMICONDUCTOR WAFERS WITH  
DETERMINED DEFECT DISTRIBUTIONS

Attorney Docket No.: WSAG 0143 PUS

**AMENDMENT UNDER 37 C.F.R. § 1.111**

Mail Stop Amendment  
Commissioner for Patents  
U.S. Patent and Trademark Office  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action dated April 13, 2006, kindly amend the above-identified application as follows:

**CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8 (FIRST CLASS MAIL)**

I hereby certify that this paper, including all enclosures referred to herein, is being deposited with the United States Postal Service as first-class mail, postage pre-paid, in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450 on:

May 9, 2006

Date of Deposit

William G. Conger  
Name of Person Signing

  
Signature